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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2812
Examiner: Stanetta D. Isaac

In Re PATENT APPLICATION of:

Applicant(s): Jun KANAMORI

Serial No.: 10/634,851

Filing Date: August 6, 2003

For: SEMICONDUCTOR DEVICE FABRICATION
METHOD USING OXYGEN ION
IMPLANTATION

Atty. Ref.: MAE 292

Please Enter
SBC 4/20/06

AMENDMENT

May 25, 2006

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Madam:

In response to the Examiner's Action mailed on February 28, 2006, please
amend the above-identified application as follows: